



Evactron®
By XEI Scientific

Evactron® E50 E-TC Plasma De-Contaminators With Wired Touchpad Control

SEM AND FIB VACUUM CHAMBER CLEANING SYSTEM

The Evactron E50 E-TC De-Contaminators are compact, high performance yet simplified plasma cleaners for Electron and Ion Beam Instruments such as SEMs, TEMs, and FIBs. The E50 E-TC delivers high power cleaning for superior resolution and imaging. Detector and probe sensitivity that are compromised by contamination are also improved after plasma cleaning.

The compact design of the Evactron E50 E-TC Plasma Radical Source (PRS) makes it a versatile solution for either SEM/FIB chambers, load locks, or sample prep chambers. Evactron plasma cleaners offer fast, effective, and powerful cleaning over a wide range of pressures, enabling high quality, artifact free images and increased efficiency of sample analysis.

System Features:

- RF Power: 75W peak, up to 50W continuous
- Dual action cleaning using plasma and UV afterglow
- Energy efficient radio frequency hollow cathode plasma (RFHC)
- "Pop" ignition at high vacuum
- Programmable power, cleaning time, number of cycles, recipes
- Wired touchpad programming
- Wide range pressure operation: 0.3 Pa/ 2 mTorr to 80 Pa/ 600 mTorr
- Alternate gas configurations available
- TMP compatible, no advance venting needed
- Fast cleaning, 100X+ faster than earlier generation Evactron models
- Non-damaging to sensitive components - no sputter etch
- PRS can be installed on the SEM chamber or the load lock
- Push button cleaning operation on Power Centre Controller
- No match or gas flow adjustments needed for plasma ignition
- TUV, NRTL, SEMI and CE compliant



Evactron® E50 E-TC Plasma Cleaner

Remote Plasma Cleaner

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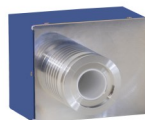
Evactron E50 Products



The **Evactron E50 E-TC Plasma De-Contaminator** was designed for facilities that prefer a wired touchpad interface for programming. The touchpad (134 x 112 x 69mm) is connected by an RS-232 cable to the controller. The simplified PRS has a small footprint and utilizes air plasma and UV afterglow to reduce hydrocarbon contamination, delivering results quickly.

Evactron E50 E-TC System Specifications:

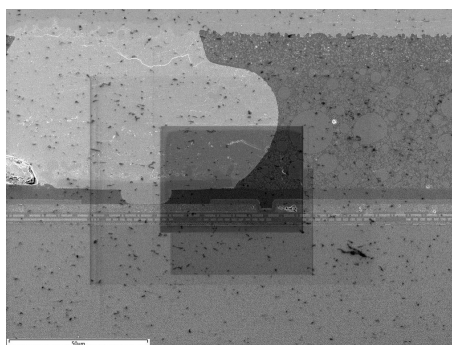
- Power Centre Controller with pushbutton operation
- Tethered touchpad communication package
- Hardware interlock
- Chassis dimensions: W x H x D: 12.25"x 3.5"x 9.34" (31 x 8.9 x 23.7cm)
- RF Power: 35 - 75 Watts at 13.56 MHz RFHC
- 100-240 VAC 50/60 Hz input
- RoHS Compliant



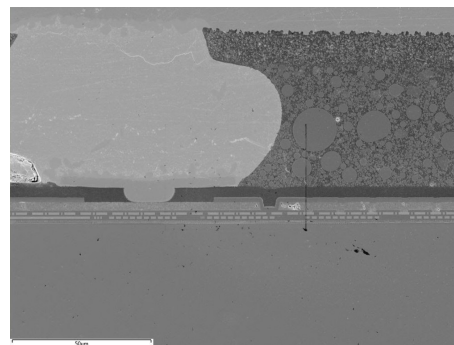
The **Evactron E50 E-TC OEM Plasma De-Contaminator** was designed for OEM integration including SEM, FIB, high vacuum, and other analytical instruments. This simplified Evactron Plasma Radical Source (PRS) has a small footprint and utilizes air plasma and UV afterglow to reduce hydrocarbon contamination, delivering artifact-free results quickly.

Evactron E50 E-TC OEM System Specifications:

- SEM/FIB host-directed control
- 2U rack mount controller for system integration
- Hardware interlock
- Powerful compact Plasma Radical Source (PRS)
- RF Power: 35 - 75 Watts at 13.56 MHz RFHC
- 100-240 VAC 50/60 Hz input
- RoHS Compliant



Before Cleaning



After Evactron Cleaning

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